

San Diego APCD
Emissions Inventory Request Form Instructions

WASTE WATER TREATMENT PLANT ODOR CONTROL SYSTEMS

Please refer to the general instructions for guidance regarding the following sections: Reporting Year, Facility Identification, Permit Information, Device Information, Stack / Ducted Emissions and Fugitive Release Emissions.

MATERIAL/ PROCESS INFORMATION

Fill in all the data fields. Complete all blanks using the specified units and answer yes or no where requested. Use a separate form to report each Site Equipment ID. Copy the blank form as needed to report each Site Equipment ID. On forms with pre-printed process information from a previously submitted inventory, asterisks (*) highlight data fields that must be updated.

Site Equipment ID: Provide the odor control equipment identification number.

Max. Odor System Flowrate (scfm): Report the maximum flowrate through the odor control system in standard cubic feet per minute.

Avg. Odor System Flowrate (scfm): Report the average flowrate through the odor control system in standard cubic feet per minute.

Equipped With: Answer "yes or no" to each of the control process types listed and describe any other odor control systems in use.

Treatment Plant Information: These items refer to the treatment plant only, apart from the odor control system.

Device Operating Schedule:

Daily Operation (hours/day): Report the average amount of hours the device operates in a typical day.

Weekly Operation (days/week): Report the average number of days the device operates in a typical week.

Annual Operation (days/year): Report the number of days the device operated during the Reporting Year.

POLLUTANT NAME (lbs/million gallons thru put)

If available, provide site specific emission factors in units of pounds released per million gallons of throughput with supporting documentation. Default emission factors will be used to estimate emissions where site-specific information is not available or not documented.

San Diego APCD
Emissions Inventory Request Form
WASTEWATER PROCESSING

REPORTING YEAR:

EIF ID : SITE RECORD ID :

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PERMIT INFORMATION :

DEVICE INFORMATION :

STACK (DUCTED EMISSIONS)
Diameter (ft): Exhaust Gas Temperature (F): Exhaust Gas Flowrate (CFM): Height Above Ground (ft): Control Device Description: Capture Efficiency (%): Volatile Control Efficiency (%): Non-Volatile Control Efficiency (%):

RELEASE (FUGITIVE EMISSIONS)
Emission Control Method: Volatile Control Efficiency (%): Non-Volatile Control Efficiency (%): Additional Information: Capture Efficiency (%):

MATERIAL/PROCESS INFORMATION
Process Description: Avg. Wastewater Thru-put (mgd): Max. Wastewater Thru-put (mgd): Equipped With: - Covers (yes/no): - Ferric Chloride Injection (yes/no): - H2O2 Injection (yes/no): - Caustic Scrubber (yes/no): - Activated Carbon (yes/no): - Biofilter (yes/no): - Other (describe): Device Operating Schedule: - Daily Operation (hours/day): - Weekly Operation (days/week): - Annual Operation (days/year):

POLLUTANT NAME	lbs pollutant/million gal thru-put

EIF ID: , SITE RECORD ID: , PERMIT: , DEVICE:

Prepared By: _____

Date: _____